

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Docket: 8183

Applicant(s): KOOPS, Hans Wilfried Peter

United States Filing Date: July 28, 2003

United States Application Serial No. : 10/628,174

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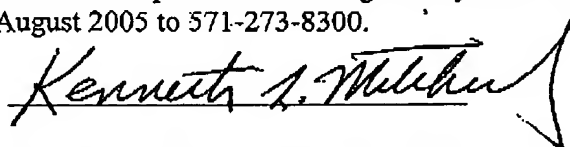
Title: PROCEDURE FOR ETCHING OF MATERIALS AT THE SURFACE WITH
FOCUSSED ELECTRON BEAM INDUCED CHEMICAL REACTION AT SAID SURFACE

Examiner: Olsen, Allan W
Art Unit: 1763

August 4, 2005

Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

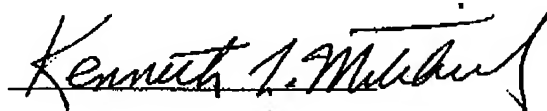
Fax Certification: I hereby certify that this correspondence is being sent by fax to the
Commissioner for Patents on this 4th day of August 2005 to 571-273-8300.



Kenneth L. Mitchell, Reg. No. 36873

RESPONSE TO ELECTION

This is in response to the office action dated July 7, 2005. Applicant wishes to elect the
invention of Group I, claims 1-3, 19-41 and 43.



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